Errata

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As stated below, there were two errors.

In the first column, third paragraph, page 211, equation (2) should have read:

$$\lambda_l^b = (\delta_l^b \wedge \neg \gamma_l) \vee (\rho_{hl}^b \wedge \psi_h^b) \vee (\rho_{vl}^b \wedge \psi_v^b).$$

In the second column, page 212, the first line of numbered paragraph 2 should have read:

2. **horizontal row test, $\eta_h = \rho_h \wedge \psi_h$:** This test is